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PPI (CATION NO	FILINODAH	FIRST ZAMED IZZEZ FOR	ALTORNEY DOCKET NO	CONFIRMATIONN
(19 7,375,0)43	12 12 2000 92 21 2002	Yue Kao	017575 0414 (TAMUS (529)	7225
Baker Botts L.L.P. 2001 Ross Avenue			EXAMINER	
Dallas, TX = 75201-2980			COLEMAN, WILLIAM D	
			ARTUNII	PAPER NUMBER
			2823	
			DATE MAILED סיפור בי	

Please find below and or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)
	09/736,043	KUO, YUE
Office Action Summary	Examiner	Art Unit
	W. David Colema	
The MAILING DATE of this communication Period for Reply	n appears on the cover	sheet with the correspondence address
A SHORTENED STATUTORY PERIOD FOR RI THE MAILING DATE OF THIS COMMUNICATION  - Extensions of time may be available under the provisions of 37 OF after SIX (6) MONTHS from the mailing date of this communication  - if the period for reply specified above is less than thirty (30) days.  - if NO period for reply is specified above, the maximum statutory period for reply within the set or extended period for reply will by second any reply received by the Office later than three months after the rearned patent term adjustment. See 37 CFR 1 704(b)	ON: FR 1 136(a) In no event howevent a reply within the statutory mining eriod will apply and will expire S statute cause the application to	ver, may a reply be timely filed  mum of thirty (30) days will be considered timely  XX (6) MONTHS from the mailing date of this communication,  become ARANDONED (35.1.5.0.8.133)
Status		
1) Responsive to communication(s) filed on		
_	This action is non-fin	
<ol> <li>Since this application is in condition for al closed in accordance with the practice un</li> </ol>	llowance except for for der <i>Ex parte Quayle</i> , **	mal matters, prosecution as to the merits is 1935 C.D. 11, 453 O.G. 213.
Disposition of Claims		
4) Claim(s) $1-30$ is/are pending in the application	ation.	
4a) Of the above claim(s) is/are with	idrawn from considera	tion.
5) Claim(s) is/are allowed		
6)  Claim(s) <u>1-30</u> is/are rejected.		
7) Claim(s) 14 is/are objected to.		
8) Claim(s) are subject to restriction a	nd/or election requirem	nent.
Application Papers		
9)☐ The specification is objected to by the Exan	niner.	
10)⊡ The drawing(s) filed on <u>12 December 2000</u>	is/are: a)⊠ accepted o	r b)⊡ objected to by the Examiner.
Applicant may not request that any objection	to the drawing(s) be held	in abeyance. See 37 CFR 1.85(a).
11) The proposed drawing correction filed on _	is: a) 🗌 approved	I b)
If approved, corrected drawings are required i	n reply to this Office action	on.
12) The oath or declaration is objected to by the	Examiner.	
riority under 35 U.S.C. §§ 119 and 120		
13) Acknowledgment is made of a claim for for	eign priority under 35	U.S.C. § 119(a)-(d) or (f).
a)⊠ All_b)□ Some * c)□ None of:		
1. Certified copies of the priority docum	ients have been receiv	red.
2. Certified copies of the priority docum	ients have been receiv	ed in Application No
3. Copies of the certified copies of the paper application from the Internationa * See the attached detailed Office action for a	l Bureau (PCT Rule 17	
14) Acknowledgment is made of a claim for dom		
a) The translation of the foreign language		
15) Acknowledgment is made of a claim for dom		
ttachment(s)	-	
Notice of References Cited (PTO-892)  Notice of Draftsperson's Patent Drawing Review (PTO-948)  Information Disclosure Statement(s) (PTO-1449) Paper No.	) 5) N	nterview Summary (PTO-413) Paper No(s) Notice of Informal Patent Application (PTO-152) Other
Patent and Trademark Office O-326 (Rev 04-01) Office	ce Action Summary	Part of Paper No. 2

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#### DETAILED ACTION

#### Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States

- 2. Claims 1, 2, 3, 4, 7, 8, 9, 10, 11 and 18 are rejected under 35 U.S.C. 102(b) as being anticipated by Gardner et al., U.S. Patent 5,350,484.
- 3. Pertaining to claims 1, 11 and 18, <u>Gardner</u> discloses a semiconductor process as claimed. See **FIGS**. **2A-2C**, where <u>Gardner</u> teaches a method for forming a conductive pattern for a semiconductor device comprising:

patterning a mask layer 4 outwardly from a conductive layer 3 of the semiconductor device, the patterning defining portions 6 of the conductive layer 3 where vias through the conductive layer 3 are desired;

exposing the semiconductor device to a plasma 10, the plasma converting the unmasked portions of the conductive layer 3 into a compound 8: and

exposing the semiconductor device to a treatment process, the treatment process selectively removing the compound (column 8, lines 22-27).

4. Pertaining to claims 2 and 28, <u>Gardner</u> teaches wherein the conductive layer **3** comprises a copper material (column 6, lines 55-56).

Pertaining to claim 3, Gardner teaches removing the mask layer 4 from the semiconductor device

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5. Pertaining to claims 4 and 20, <u>Gardner</u> teaches removing the mask layer 4 after removing the compound 8.

- 6. Pertaining to claims 7 and 15, <u>Gardner</u> teaches providing a barrier layer **2** between the conductive material **3** and the substrate (not numbered).
- 7. Pertaining to claims 8 and 14, <u>Gardner</u> teaches wherein the conductive material 3 comprises a copper material, and wherein exposing the semiconductor device to a plasma 10 comprises exposing the semiconductor device to a chlorine-containing gas (column 7, line 26).
- 8. Pertaining to claims 9, 23, 24, 25, 26, 29 and 30, <u>Gardner</u> teaches wherein the compound comprise a copper chloride material **8**, and wherein exposing the semiconductor device to a treatment process comprises exposing the semiconductor device to a hydrogen chloride solution to remove the copper chloride material (See table III).
- 9. Pertaining to claims 10, 17 and 19, <u>Gardner</u> teaches wherein the mask layer comprises a photoresist material 5.
- 10. Pertaining to claim 13. <u>Gardner</u> teaches wherein forming a conductive layer 3 comprises forming a copper layer outwardly from the substrate.
- 11. Pertaining to claims 16, 22 and 27, <u>Gardner</u> teaches wherein exposing the electronic device to a plasma comprises controlling the exposure of the electronic device to the plasma 10 to form a substantially perpendicular interface between the masked conductive material 3 and the compound 8.

### Claim Rejections - 35 USC § 103

12. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

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(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

- 13. Claims 5, 12 and 21 are rejected under 35 U.S.C. 103(a) as being unpatentable over Gardner et al., U.S. Patent 5.350,484 as applied to claims 1-4, 7-11, 13-20 and 22-30 above.
- Gardner teaches a semiconductor process substantially as claimed, however, Gardner fails to teach the selection of removing the masking layers before removing the compound. Applicant is reminded that selection of any order of performing process steps is prima facie obvious in the absence of new or unexpected results. In re Burhans, 154 F.2d 690, 69 USPQ 330 (CCPA 1946). However, in the absence of new or unexpected results, the mere reversal of the order of performing process steps has been held to be prima facie obvious. In re Burhans, 154 F.2d 690, 69 USPQ 330 (CCPA 1946).
- 15. Claim 6 is rejected under 35 U.S.C. 103(a) as being unpatentable over Gardner et al., U.S. Patent 5,350,484 as applied to claims 1-4, 7-11, 13-20 and 22-30 above, and further in view of Ye et al., U.S. Patent 6,010,603.
- 16. Gardner discloses a semiconductor process substantially as claimed as discussed above. However, Gardner fails to teach wherein exposing the semiconductor device to a treatment process comprising: exposing the semiconductor device to a substantially inert atmosphere; and heating the semiconductor device to between 300 and 800 degrees Celsius to remove the compound. Ye teaches exposing the semiconductor device to a substantially inert atmosphere and heating the semiconductor device within the range as claimed to remove the compound. See column 13, lines 50-60, where Ye teaches the gas feed rates to the etch chamber were 140 secm of argon, 15 secm of chlorine, and 5 secm of N<sub>2</sub>. The preferred substrate temperature is

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preferably less than about 350° C. In view of <u>Ye</u>, it would have been obvious to one of ordinary skill in the art to incorporate the compound removal process of <u>Ye</u> into the <u>Gardner</u> semiconductor process because it helps volatilize some species such as CuCl<sub>x</sub>, enabling these species to leave the film surface (column 13, lines 60-62).

## Specification

17. Claim 14 is objected to because of the following informalities: the term "exposing the electronic device to a plasma appears twice in the same sentence. Appropriate correction is required.

#### Conclusion

18. Any inquiry concerning this communication or earlier communications from the examiner should be directed to W. David Coleman whose telephone number is 703-305-0004. The examiner can normally be reached on 9:00 AM-5:00 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor. Wael M. Fahmy can be reached on 703-308-4918. The fax phone numbers for the organization where this application or proceeding is assigned are 703-308-7722 for regular communications and 703-308-7721 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0956.

W. David Coleman Examiner Art Unit 2823

WDC February 16, 2002

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